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INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Docket: 748-58343	App:
	Applicant: Austen et al.	
	Filed: Herewith	Art Unit:

U.S. PATENT DOCUMENTS

Init.*		Number	Date	Name	Class	Sub	Filed

FOREIGN PATENT DOCUMENTS

		Number	Date	Country	Class	Sub	
KM		PCT/US00/25002	03/29/01	Schultz et al.			

OTHER DOCUMENTS

KM		Jones, "Advances in Thermal Profiling for Reflow Process Control," Presented at SMTA 2000 Conference (2000)
KM		Kazmierowicz, "The Science Behind Conveyor Oven Thermal Profiling," http://www.kicthermal.com/library/tsbcotp.html , (1992)
KM		"The Process Window Index: A Method For Quantifying Thermal Profile Performance," 3 pages, (date and author unknown)
KM		KIC Pilot™ Reflow Expert Systems, http://www.kicthermal.com/products/pilot.html , (2000)

EXAMINER: <i>John McHenry</i>	DATE: <i>7/24/03</i>
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*Examiner: Initial if considered, whether or not in conformance with MPEP 609; draw line through cite if not in conformance and not considered. Send copy.